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SHEET 1 OF 1

INFORMATION DISCLOSURE STATEMENT
BY APPLICANT

(USE SEVERAL SHEETS IF NECESSARY)

APPLICANT
RainaFILING DATE
January 29, 2002GROUP
2877

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
GP	1.	4,125,446	11/14/78	Hartsough et al.			
	2.	4,792,842	12/20/88	Honma et al.			
	3.	5,147,819	09/15/92	Yu et al.			
	4.	5,229,331	07/20/93	Doan et al.			
	5.	5,358,908	10/25/94	Reinberg et al.			
	6.	5,372,973	12/13/94	Doan et al.			
	7.	5,923,953	7/13/99	Goldenberg Barany et al.			
	8.	6,154,188	11/28/00	Learn et al.			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

GP	9.	Takagi et al., "P2.2-3 Characterization of Al-Nd Alloy Thin Films for Interconnections of TFT-LCDs" Asia Display 1995, 4 pages.					
GP	10.	Takayama et al., "Al-Sm and Al-Dy alloy thin films with low resistivity and high thermal stability for microelectronic conductor lines", Thin Solid Films 289, 1996 pp. 289-294.					
GP	11.	Kim et al., "22.2 Pure Al and Al-Alloy Gate-Line Processes in TFT-LCDs", SID 96 Digest, pp. 337-340.					

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SEP 09 2002
TC 1700
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APR 25 2002
TECHNOLOGY CENTER 2800

EXAMINER	<i>Yoon Hwang</i>	DATE CONSIDERED	5/28/03
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